

INFORMATION DISCLOSURE CITATION  
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ATTY DOCKET NO. WLJ.051D	SERIAL NO. 10/654 404 NEW
Knut Beekman et al.	
FILING September 4, 2003	GROUP TO BE ASSIGNED

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
hj	A 5,242,860	09/1993	NULMAN et al.			
hj	B 5,523,259	06/1996	MERCHANT et al.			
hj	C 5,278,448	01/1994	FUJI			
hj	D 5,843,843	12/1998	LEE et al.			
hj	E 5,462,890	10/1995	HWANG et al.			
hj	F 6,143,128	11/2000	AMEEN et al.			
hj	G 5,204,192	03/2001	ZHAO et al.			
hj	H 6,077,571	06/2000	KALOYEROS et al.			
hj	I 5,899,720	05/1999	MIKAGI			
hj	J 5,591,663	01/1997	NASU et al.			
hj	K 5,851,917	12/1998	LEE			

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
hj	L 11040518	02/1999	JAPAN				
hj	M 8274076	10/1996	JAPAN				
hj	N 7142412	06/1995	JAPAN				
hj	O JP-9246212-A	09/1997	JAPAN				
hj	P WO 88/02033	03/1998	PCT				

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hj	Q	C.R. Aita, "Basal orientation aluminum nitride grown...", J. Appl. Phys. 53(3), March 1982, pages 1807-1808.
hj	R	Hwan-Chul Lee et al., "Effects of sputtering pressure and nitrogen concentration on the preferred orientation of AlN thin films," Journal of Materials Science: Materials in Electronics (1994) 221-225.

EXAMINER <i>hj</i>	DATE CONSIDERED <i>5. 10. 2004</i>
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>MM</i>	S	H1792-B2	04/1999	MORAN et al.			
<i>MM</i>	T	4,959,136	09/1990	HATWAR			
<i>MM</i>	U	4,957,604	09/1990	STEININGER			
<i>MM</i>	V	6,001,736	12/1999	KONDO et al.			
<i>MM</i>	W	5,795,823	08/1998	AVANZINO et al.			
<i>MM</i>	X	6,025,762	02/2000	ROY et al.			
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<i>MM</i>	Y	0 327 888 A2	08/1989	EPO			
<i>MM</i>	Z	0 583 736 A1	02/1994	EPO			
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<i>MM</i>	BB	Hiroshi Okano et al., "Preparation of C-Axis Oriented AlN Thin Films by Low-Temperature Reactive Sputtering," Jpn. J. Appl. Phys. Vol. 31 (1992), Pt. 1, No. 10, pages 3446-3451.					
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